**ETH**Eidgenössische Technische Hochschule Zürich  
Swiss Federal Institute of Technology Zurich

# A building block for a scalable quantum computing architecture

Trapped-Ion Quantum Information Group, ETH Zürich

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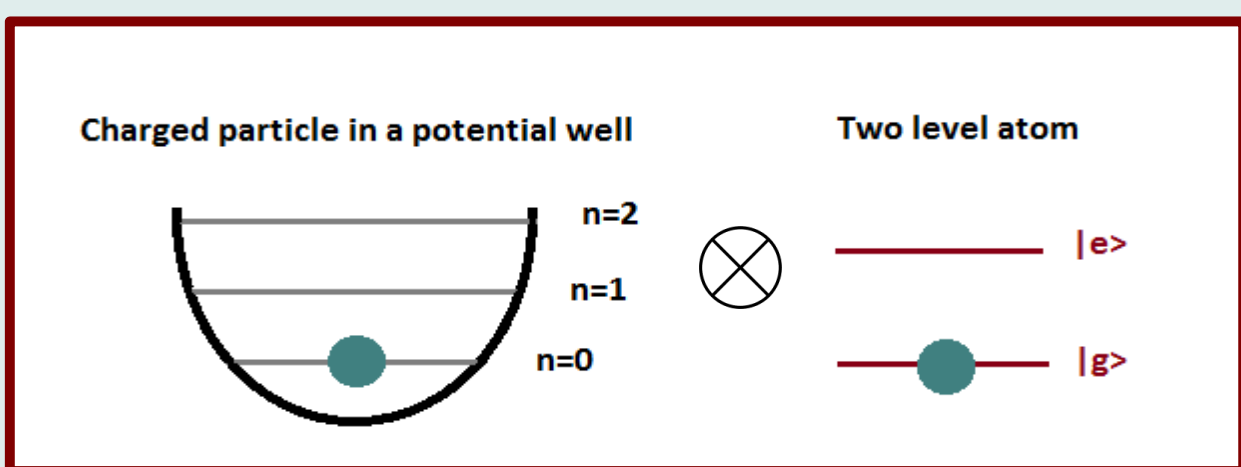
**QSIT** Quantum  
Science and  
Technology  
National Centre of Competence in Research**FNSNF**

## Towards a scalable quantum computer

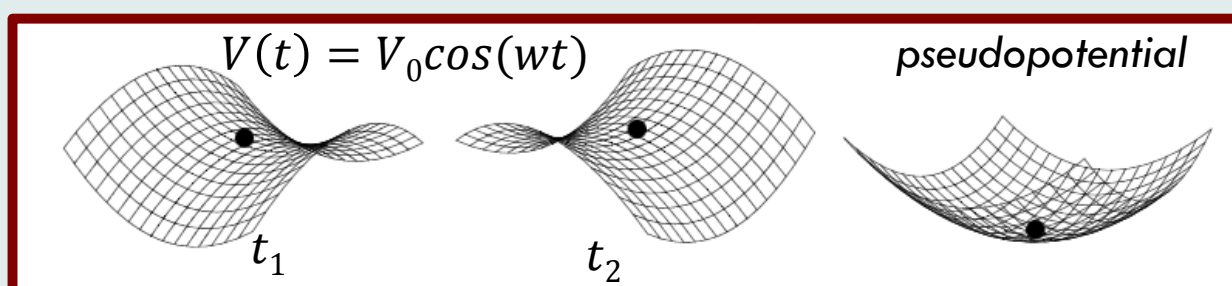
### QCCD architecture: one approach to scalable devices

- Large number of independent **trapping units**.
- **Junctions** allow scalability by connecting trap units in two dimensions.
- Quantum information, encoded in the ions, is transferred by physically shuttling the ions to different trap units.
- Integrated optics are necessary for compact and scalable devices.

**Ion as a qubit:** two internal energy levels are identified as the quantum states  $|0\rangle$  and  $|1\rangle$ , two qubits are coupled via their motion.



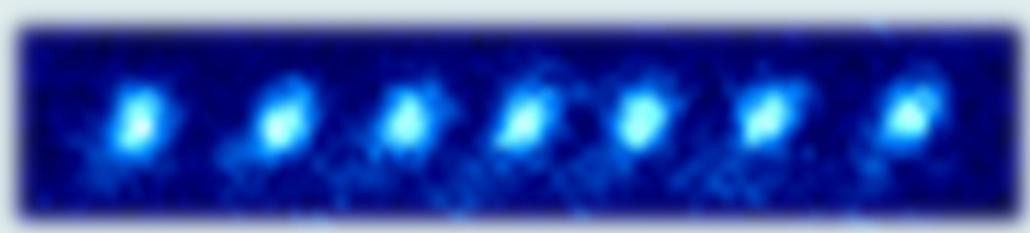
**Trapping the ion:** RF & DC electric fields confine the ion in all directions, DC fields are used to transport the ions, split and recombine potential wells.



**Manipulating the ion:** laser light is used to cool the ion, initialize its state and realize a universal set of quantum gates, including two-qubit gates and qubit readout.

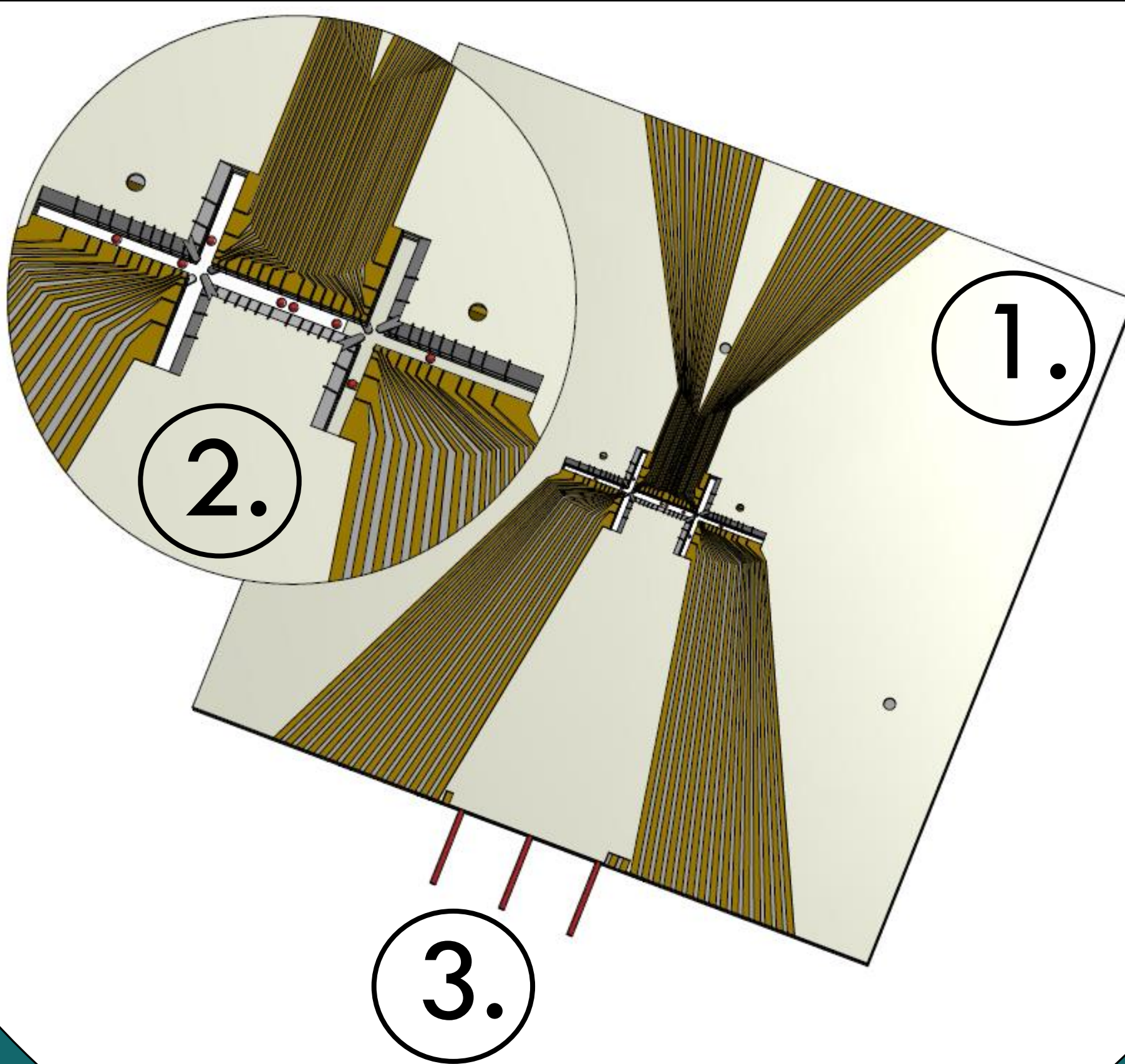
**This work:** a double-junction, multi-species ion trap with integrated laser delivery through optical lensed fibres, designed for:

- parallel operations
- Decoherence Free Subspace (DFS) ion transport across the junctions
- manipulation of long chains of ions



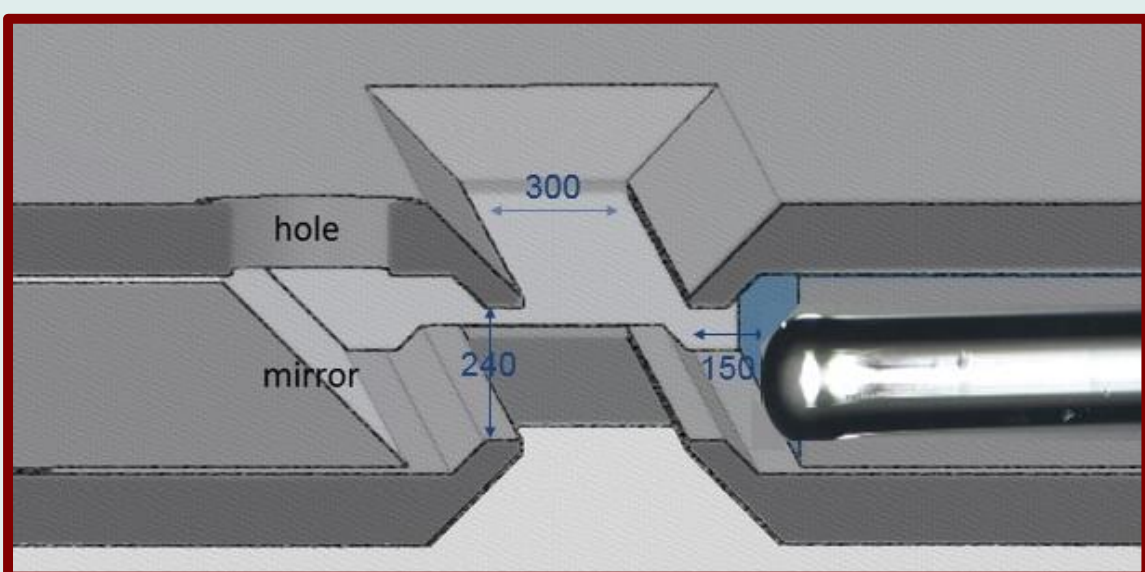
TIQI, ETH, string of ions

## THIS WORK: a 3D double junction ion trap with integrated optical delivery for scalable quantum computation

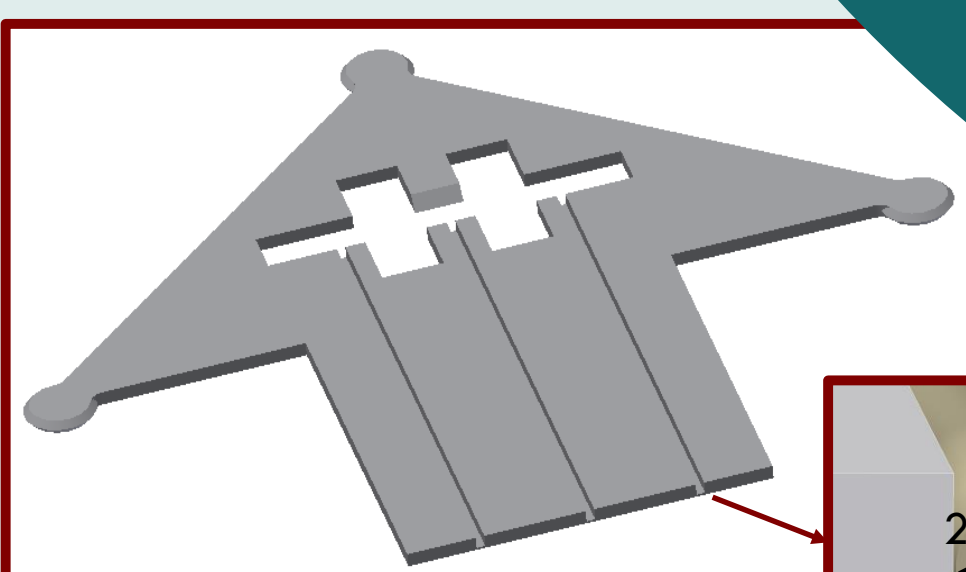


## 3. Optical integration: lensed fibres

**Previous technology:** ions are addressed using free space laser beams: requires bulky optics and custom objectives, not easily scalable.

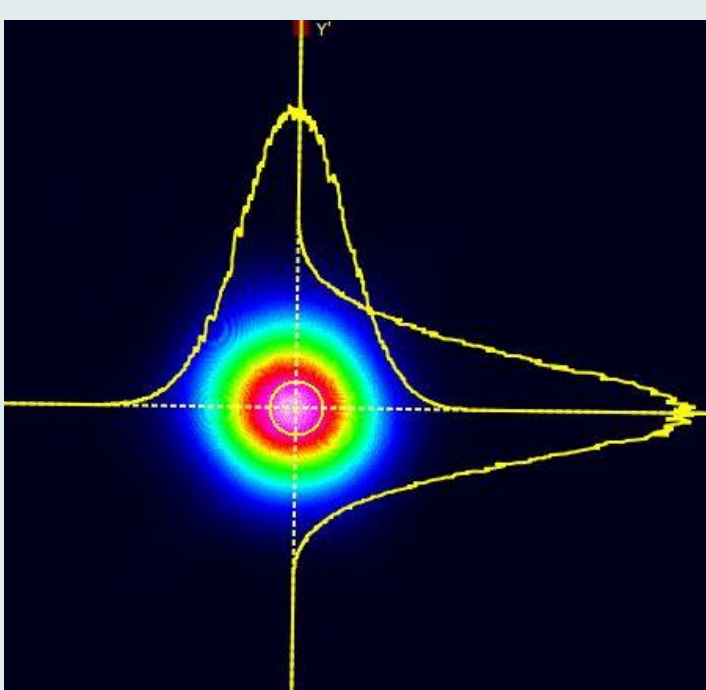
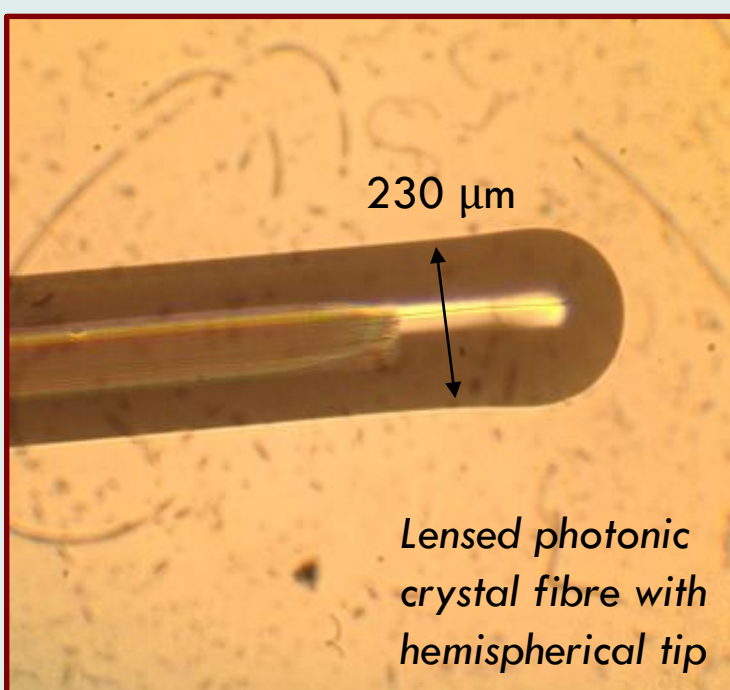


The middle wafer serves as a holder for 3 lensed fibres



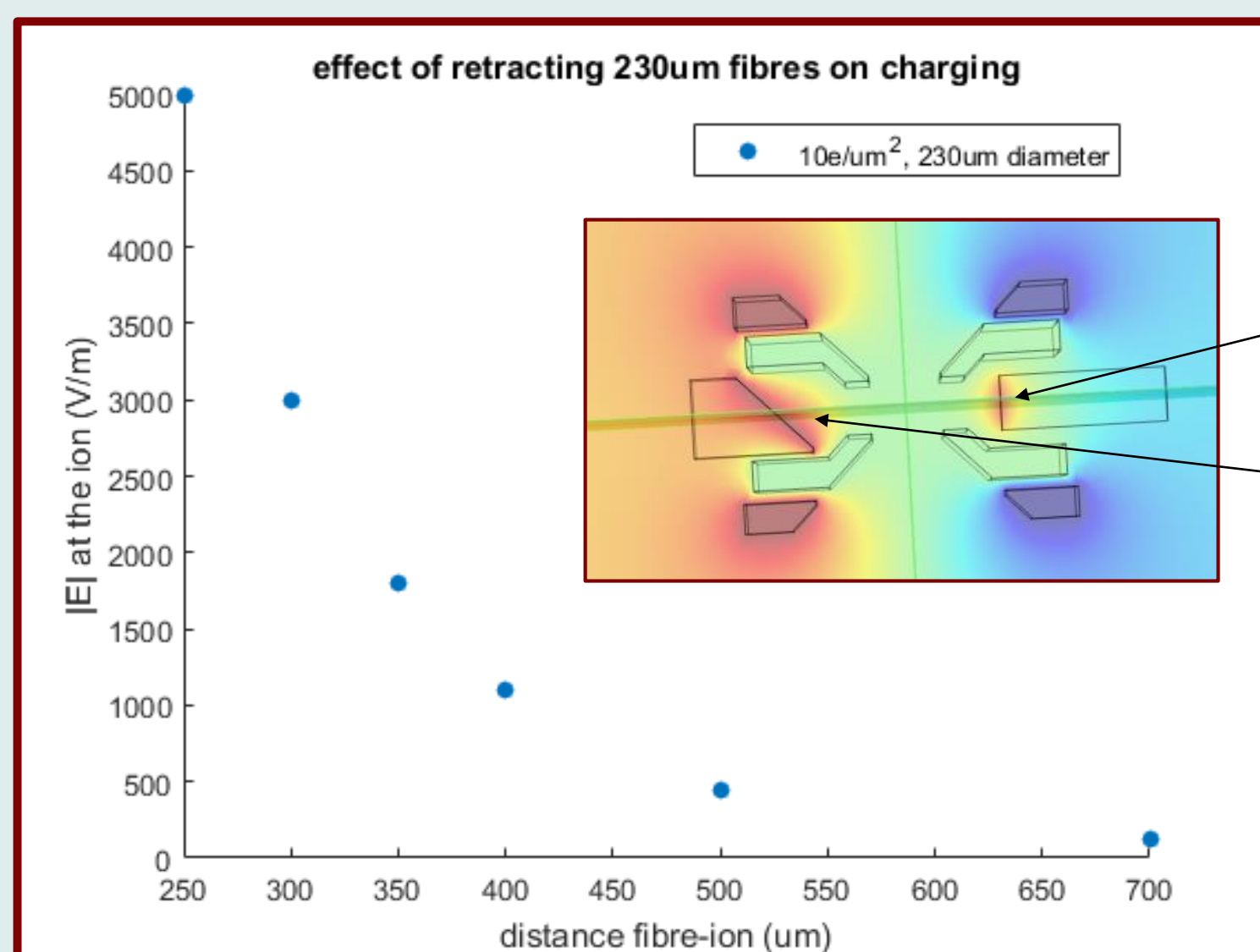
Squared groove with PC lensed fibre

- Lensed fibres bring laser light to the ions at the experimental zones.
- Photonic Crystal Fibres (PCFs) have lenses at their tip to focus the light to 20  $\mu\text{m}$  (FWHM), up to 500  $\mu\text{m}$  away.
- Lenses produced via rounds of polishing.
- Hemispherical lens creates a Gaussian beam profile (Fig. on the right).
- Lensed fibres are glued into square grooves.



### Challenges and solutions of integrating optics

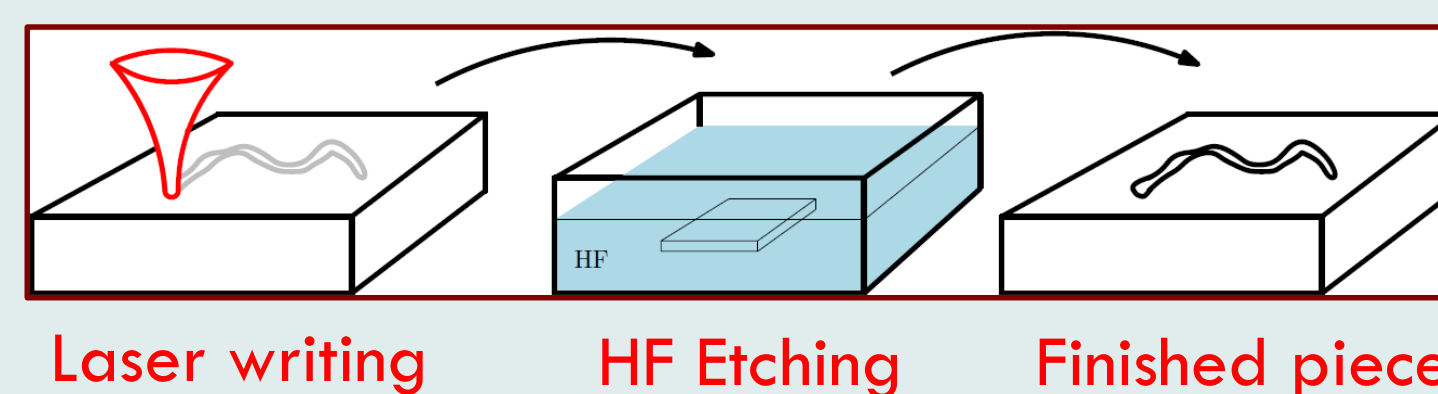
- Glass fibres tip accumulates charges, producing stray electric fields.
- Solution: **bias electrodes** serving also as **mirrors** for extracting light from setup.
- Alternative: coat fibres with Indium Tin Oxide (ITO), to make them electrically shielding, yet transparent at IR wavelengths (700-800 nm). Expected transparency 70-85 %.



## 1. Precise wafer alignment

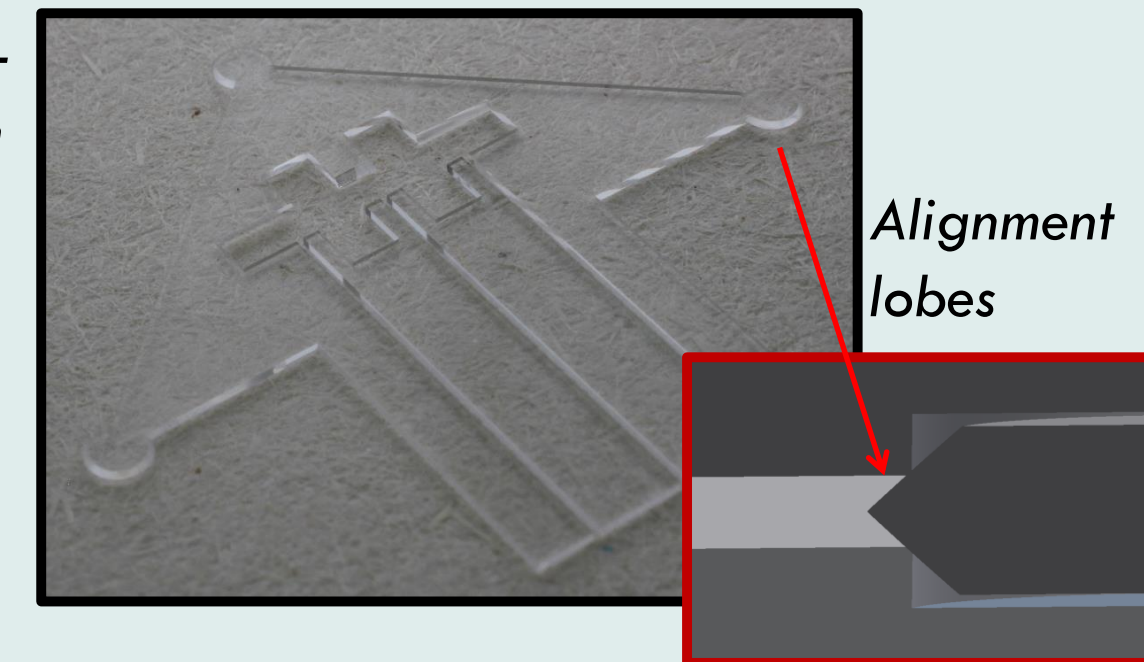
**Previous traps alignment:** alumina trap wafers manually assembled, leading to misalignment of up to 10  $\mu\text{m}$ . Misalignment affects the location of the minimum of the pseudopotential in which the ions are trapped.

### New wafer manufacturing technology: subtractive laser writing (FemtoPrint)



- Allows for the creation of small, precise structures on wafers.
- Alignment of wafers by mechanical guides less prone to misalignment errors.
- Easy, fast and precise assembly.

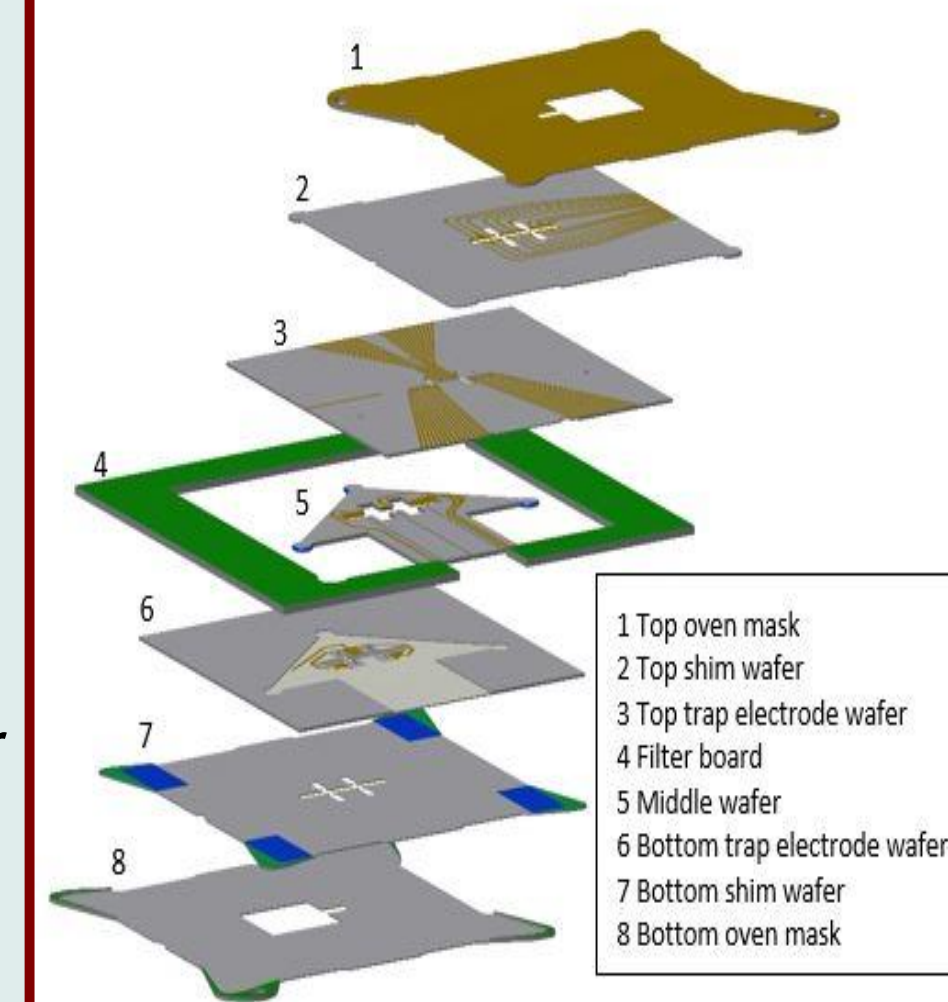
### Our new traps using this technology: a cavity integrated 3D trap and a double junction 3D trap



Surface roughness 3D surfaces < 200 nm  
Surface roughness vertical < 80 nm  
Horizontal precision  $\approx$  1  $\mu\text{m}$   
Vertical precision  $\approx$  5  $\mu\text{m}$

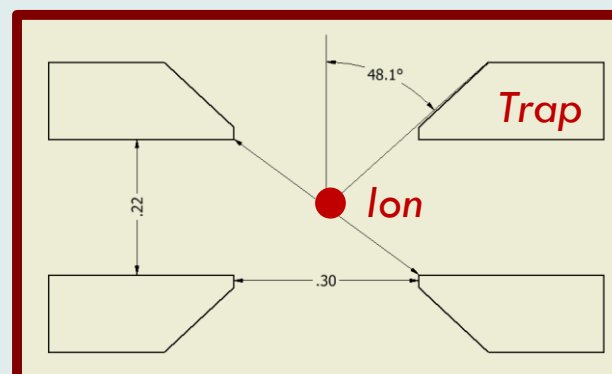
Double junction trap consists of 7 wafers:

- two main trapping wafers
- middle wafer (spacer and optical integration)
- two shim wafers for compensation
- two oven masks



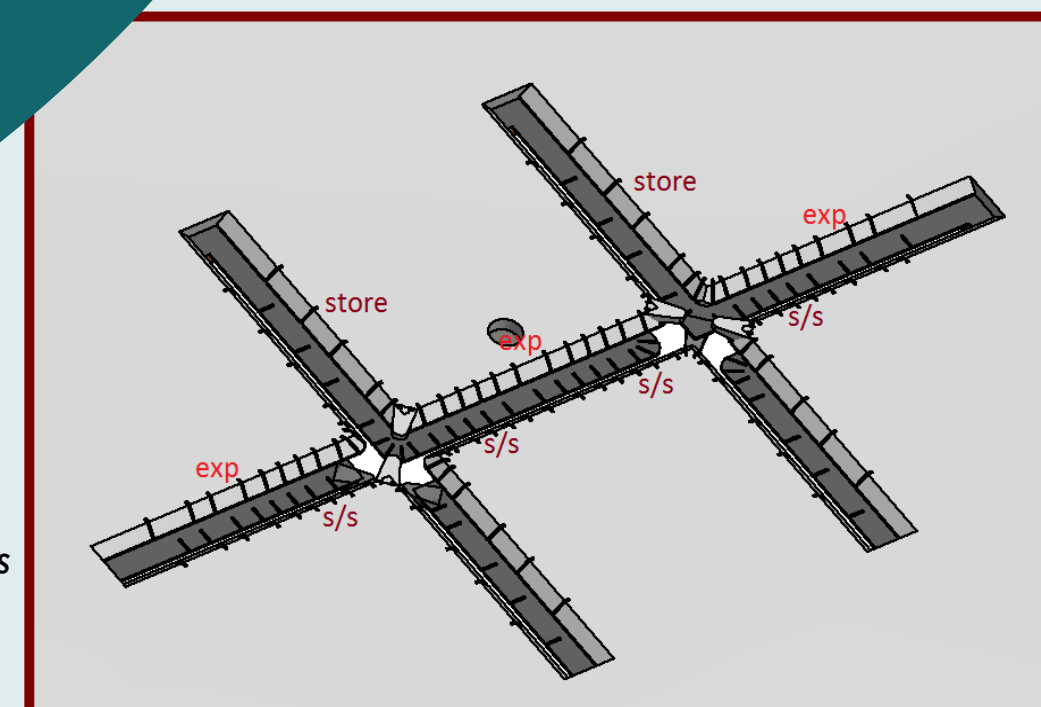
## 2. Double junction trap

Side view: optical access angle and electrodes distance

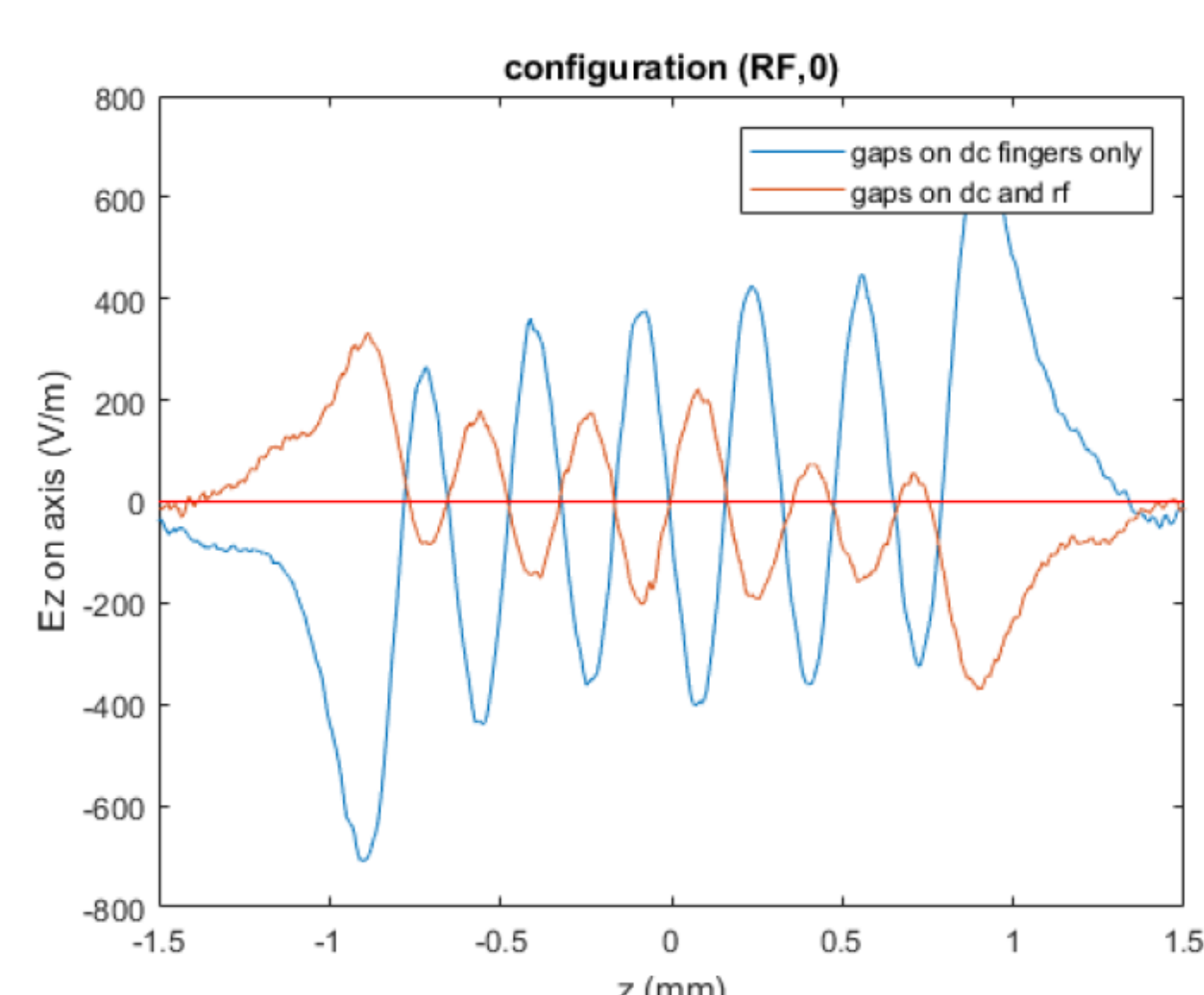
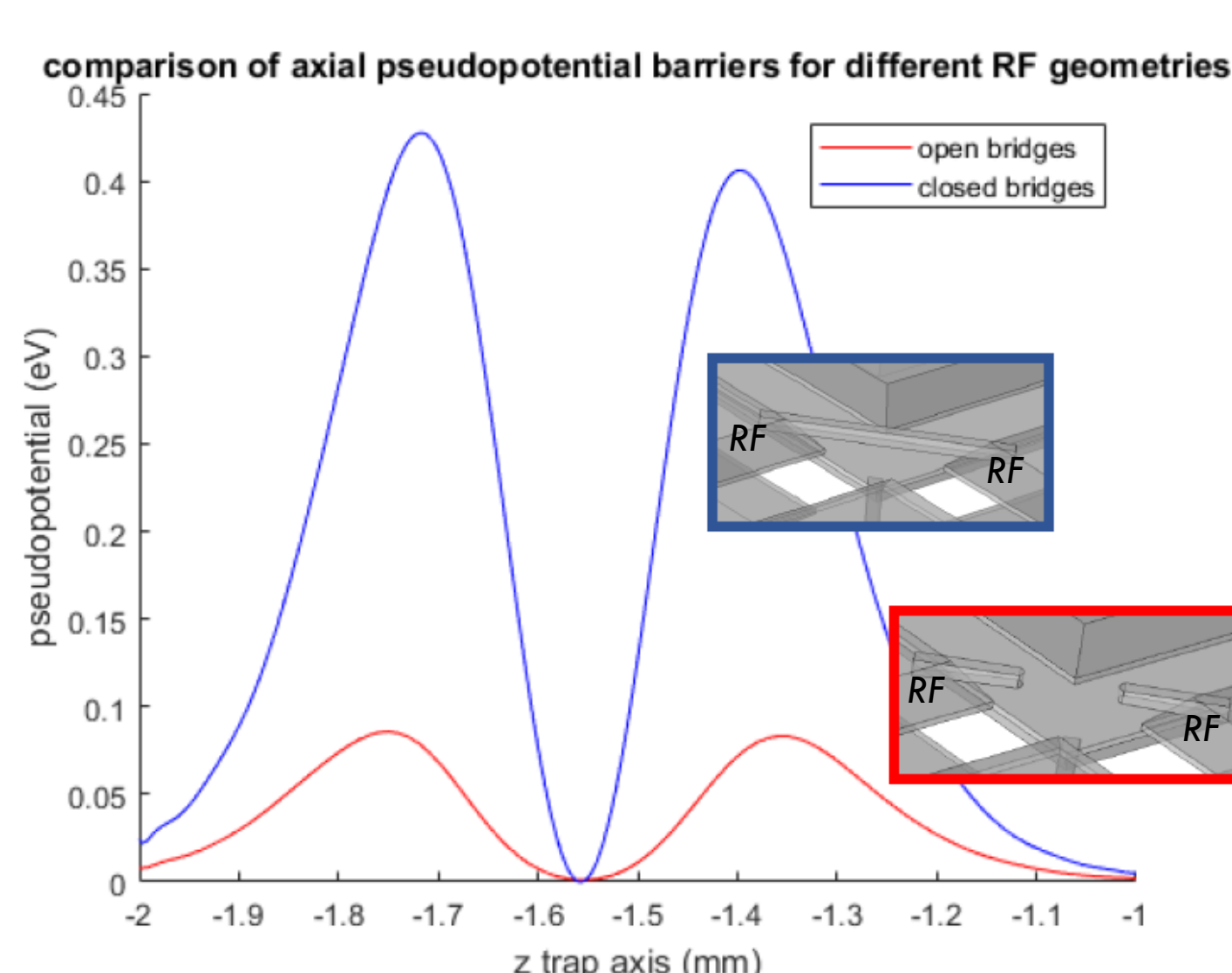


### Design & trapping zones

- two X junctions
- 145 total electrodes (ca 100 control electrodes).
- two main trapping wafers (total stack of 7).
- electrode-ion distance: 185  $\mu\text{m}$
- three independent experimental zones.
- laser optical access angle to the ion: 48°.



- Symmetry of the electric fields needs to be broken to confine at the centre of the junction.
- Bridges connecting the RF electrodes break the symmetry but introduce **axial pseudopotential barriers** (Fig. below: FEM simulation of pseudopotential on axis).
- Shaping RF bridges allows for pseudopotential barrier's height minimization.
- **Open bridges** create lower pseudopotential barriers (0.1-0.2 eV) than full bridges.
- Segmenting the RF electrodes like the DC electrodes reduces micromotion.



## Outlook

- Fabrication of the trap carried out in the ETH cleanroom using electron beam evaporation of gold.
- Experiments with the double junction trap: DFS ion transport across junctions, parallel control of ions, manipulation of long chains of ions towards the understanding of condensed matter problems.